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	Application No.	Applicant(s)	
Notice of Allowability	10/028,610	OMSTEAD ET AL.	
	Examiner	Art Unit	
	Matthew J Song	1765	 - <u>-</u> -
The MAILING DATE of this communication app All claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85 NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT F of the Office or upon petition by the applicant. See 37 CFR 1.31	S (OR REMAINS) CLOSED b) or other appropriate comm RIGHTS. This application is	in this application. If not included nunication will be mailed in due c	d ourse. THIS
1. This communication is responsive to 11/22/2004.	•		
2. ☑ The allowed claim(s) is/are <u>1-11,13-21 and 23-31</u> .			
3. $igotimes$ The drawings filed on <u>19 December 2001</u> are accepted by	y the Examiner.		
4. Acknowledgment is made of a claim for foreign priority of a) All b) Some* c) None of the: 1. Certified copies of the priority documents have 2. Certified copies of the priority documents have 3. Copies of the certified copies of the priority documents have 1. Copies of the certified copies of the priority documents have 1. Certified copies of the certified copies of the priority documents have 1. Certified copies not received:	ve been received. ve been received in Applicat	on No	on from the
Applicant has THREE MONTHS FROM THE "MAILING DATE noted below. Failure to timely comply will result in ABANDON THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.		e a reply complying with the requ	uirements
 A SUBSTITUTE OATH OR DECLARATION must be subr INFORMAL PATENT APPLICATION (PTO-152) which given 			OTICE OF
6. ☐ CORRECTED DRAWINGS (as "replacement sheets") mu (a) ☐ including changes required by the Notice of Draftsper 1) ☐ hereto or 2) ☐ to Paper No./Mail Date (b) ☐ including changes required by the attached Examine Paper No./Mail Date Identifying indicia such as the application number (see 37 CFR each sheet. Replacement sheet(s) should be labeled as such in	rson's Patent Drawing Revieus r's Amendment / Comment of 1.84(c)) should be written on	or in the Office action of the the drawings in the front (not the	back) of
7. DEPOSIT OF and/or INFORMATION about the dep attached Examiner's comment regarding REQUIREMENT	osit of BIOLOGICAL MA ^T I FOR THE DEPOSIT OF B	TERIAL must be submitted. N IOLOGICAL MATERIAL.	ote the
		• .	
Attachment(s)			
1. ☑ Notice of References Cited (PTO-892)	<u> </u>	nformal Patent Application (PTC	-152)
2. Notice of Draftperson's Patent Drawing Review (PTO-948)		Summary (PTO-413), ./Mail Date	
3. Information Disclosure Statements (PTO-1449 or PTO/SB Paper No./Mail Date		s Amendment/Comment	
4. ☐ Examiner's Comment Regarding Requirement for Deposit	8. 🛛 Examiner	s Statement of Reasons for Allov	wance
of Biological Material	9. 🗌 Other	<u>_</u> .	
		NADINE G. NOR SUPERVISORY PATENT	

DETAILED ACTION

EXAMINER'S AMENDMENT

Election/Restrictions

1. This application is in condition for allowance except for the presence of claims 12, 22 and 32 to an invention non-elected without traverse. Accordingly, claims 12, 22 and 32 have been cancelled.

Allowable Subject Matter

- 2. Claims 1-11, 13-21, and 23-31 are allowed.
- 3. The following is an examiner's statement of reasons for allowance: The closest prior art Gadgil et al (US 5,879,459) and Sandhu et al (US 2002/0195056 A1). Gadgil et al teaches a multi-wafer sequential deposition module having a plurality of overlapping wafer stations, rotating the wafers between the stations and rotating process gases located within the deposition module. Gadgil et al does not teach or suggest rotating the plurality of process gases in a sequential fashion among the plurality of non-overlapping wafer stations. Sandhu et al teaches versatile atomic layer deposition apparatus employing separate reactor chambers with stationary process gases and rotating the wafers between the two chamber to allow different optimized processing conditions in each reactor ([0047]). Sandhu et al does not teach or suggest rotating the process gases in a sequential fashion among the plurality of wafer stations.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue

Art Unit: 1765

fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Conclusion

4. The prior art made of record and not relied upon is considered pertinent to applicant's disclosure.

Suntola et al (US 4,389,973) teaches rotation of wafers to perform atomic layer deposition (Fig 8-9).

Suntola et al (US 4,058,430) teaches rotation wafers to different reactors to perform atomic layer deposition (Fig 1-5 and col 4, ln 45-67).

5. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Matthew J Song whose telephone number is 571-272-1468. The examiner can normally be reached on M-F 9:00-5:00.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Nadine Norton can be reached on 571-272-1465. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Application/Control Number: 10/028,610 Page 4

Art Unit: 1765

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Matthew J Song Examiner Art Unit 1765

MJS

NADINE G. NORTON SUPERVISORY PATENT EXAMINER